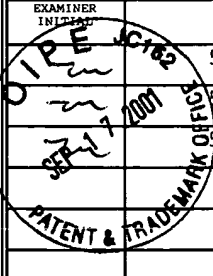




Form PTO-1449	ATTY DOCKET NO. 0459-0611P	APPLICATION NO. 09/867,606
<b>INFORMATION DISCLOSURE CITATION IN AN APPLICATION</b>  (Use several sheets if necessary)	APPLICANT Ib JOHANNSEN, et al.	
	FILING DATE May 31, 2001	GROUP 2644

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						YES	NO
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	EP 0 8 9 9 0 9 3	1999-03-03	EUROPE				

**OTHER DOCUMENTS** (Include Name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.) date, page(s), volume-issue number(s), publisher, city and/or country where published.

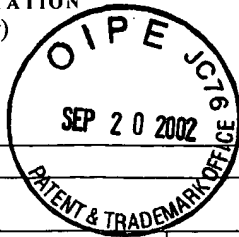
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ATTORNEY DOCKET NO.	SERIAL NO.
45900-000611/US	09/867,606
APPLICANT	
Ib JOHANNSEN et al.	
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OTHER DOCUMENTS (including Author, Title, Date, Pertinent Pages, etc.)

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